

REFERENCE NUMERALS

8143/ETCH/DRIE/JB

1	Substrate Processing System
10	Base block
12a	Processing Chamber
12b	Processing Chamber
12c	Processing Chamber
12d	Processing Chamber
14a	Load Lock Chamber
14b	Load Lock Chamber
16	Conveying Chamber
20	Reaction chamber
22	Electrode
24	Electrode
26	Device
28	HF power Supply Unit
30	Gas Supply System
30a	Gas Supply Source
30f	Gas supply source
32	Conduit
34	Vacuum Pump
36	Exhaust Pipe
40	Metal wiring Layer
40a	Insulator layer
40b	Metal Wiring layer
42	Insulator Layer Stack
42	Insulator portion
44	Barrier layer
46	Insulator layer
48	Insulator layer
50	Mask
52	Hole
52	Trench - [0080]
54	Resist mask
56	Mask
58	Trench
60	Surface
70a	Oxygen supply source